

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Date March 21, 2008

In re the Application of

Shigehiro NISHINO et al.

Group Art Unit: 1792

Application No.: 10/520,141

Examiner: M. SONG

Filed: September 1, 2005

Docket No.: 122261

For: LARGE-DIAMETER SIC WAFER AND MANUFACTURING METHOD THEREOF

**LARGE ENTITY PETITION FOR 1st - 3rd EXTENSION
OF TIME UNDER 37 C.F.R. §1.136(a) AND
TRANSMITTAL OF FEE UNDER 37 C.F.R. §1.17**

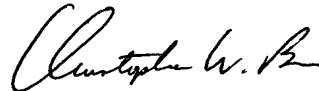
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is a Request for Continued Examination in the above-identified patent application. The shortened statutory period having expired February 26, 2008, an extension of time for a period of one month is hereby requested.

The fees associated with this filing under 37 C.F.R. §1.136(a) are being paid electronically with this filing. The Commissioner is hereby authorized to charge any additional fee (or credit any overpayment) associated with this communication to Deposit Account No. 15-0461.

Respectfully submitted,



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<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>
